

An Over 100 W CW Output Power Amplifier Using AlGaIn/GaN HEMTs

Toshihide Kikkawa¹⁾, Eizo Mitani²⁾, Kazukiyo Joshin¹⁾, Shigeru Yokokawa³⁾, Yasunori Tateno³⁾

1) Fujitsu Laboratories Ltd. 10-1 Morinosato-Wakamiya, Atsugi, 243-0197, JAPAN

2) Fujitsu Compound Semiconductor, Inc. 2355 Zanker Road, San Jose, CA, 95131, U.S.A.

3) Fujitsu Quantum Devices Ltd. 1000 Kamisukiahara, Nakakoma-gun, Yamanashi, 409-3883, JAPAN

E-mail : EMitani@fcsi.fujitsu.com, Phone : +1- 408-232-9500

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Abstract

We describe high power 150 W CW output power 36-mm gate-periphery AlGaIn/GaN HEMTs on a SiC substrate with a power added efficiency (PAE) of 54% operated at 63 V drain bias voltage (Vds). Vds dependence of third order-intermodulation (IM3) was also characterized at Vds up to 50 V. Preliminary reliability was characterized using a RF power stress test. A CW P_{3dB} RF-power measurement at Vds of 60 V exhibited good reliability for 1000 h.

INTRODUCTION

AlGaIn/GaN-based high electron mobility transistors (HEMTs) are promising for microwave power applications, including wireless base stations. There are many reports related to high output power characteristics [1-2]. However, not many papers exhibited high efficiency characteristics using a large gate-periphery device operated at over 40 V drain bias voltage. Base station system demands high efficiency from amplifier, requiring low quiescent bias current. In this paper, we demonstrate high power performance near class-B operation. To obtain higher RF-power and efficiency, we have to suppress frequency dependent instabilities, such as large transconductance (gm) dispersion, gate-lag and current collapse. We controlled the polarization-induced surface charge by n-type doping in a thin GaN cap on AlGaIn and stabilized n-GaN-surface between electrodes using SiN [3]. A 150 W CW saturation power was achieved at a 63 V operation with a PAE of 54% and a linear gain of 12.9 dB [4].

In addition, a low distortion characteristic near class-B operation is required for the base stations using digitally modulation scheme such as IMT-2000. The crest factor of a peak to average power ratio is as high as 8 dB. Therefore, it is important to consider the distortion at an average power level 8 dB back-off from saturation level. Thus, in addition to the high saturation power (Psat), high efficiency and low distortion at 8-10 dB backed-off power level from Psat is required. Moreover, pre-distortion systems can better predict the pre-distorted input signal if the device presents a simple monotonic IMD profile without sweet spots. We obtained a superior linearity profile for a 1mm-gate periphery

AlGaIn/GaN HEMT [5] biased at 30 V. We also studied distortion characteristics for larger gate-peripheries.

Reliability has become an important issue to be discussed in the manufacturing of AlGaIn/GaN-HEMTs. For this purpose, we submitted the device to RF stress to investigate stability of HEMT performance under continuous power operation. A CW P_{3dB} RF-power measured at 60V drain bias exhibited good reliability for 1000 h.

DEVICE TECHNOLOGY

To suppress instabilities related to frequency dispersion, such as large-signal current collapse and gm dispersion, we introduced an n-type doped GaN cap layer into the AlGaIn/GaN HEMTs structure to control the polarization-induced surface charges [3]. Figure 1 shows the device structure on SiC substrates investigated in this study. Detailed fabrication method was described in the previous papers [3-6].

Recessed ohmic technology was introduced to obtain lower ohmic contact resistance [7]. Only n-type doped GaN cap layer was removed. Figure 2 shows etching depth

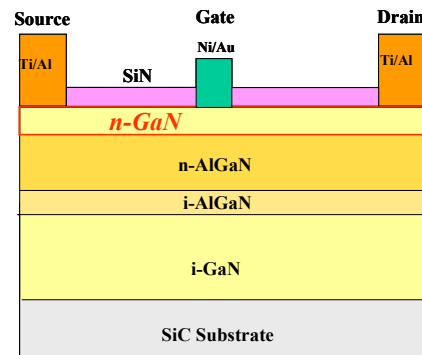


Fig.1. Schematic drawing of investigated the surface-charge-controlled n-GaN-cap structures. Thin n-type GaN cap layer was grown on AlGaIn/GaN structure. SiN passivation was formed on GaN cap layer between electrodes.

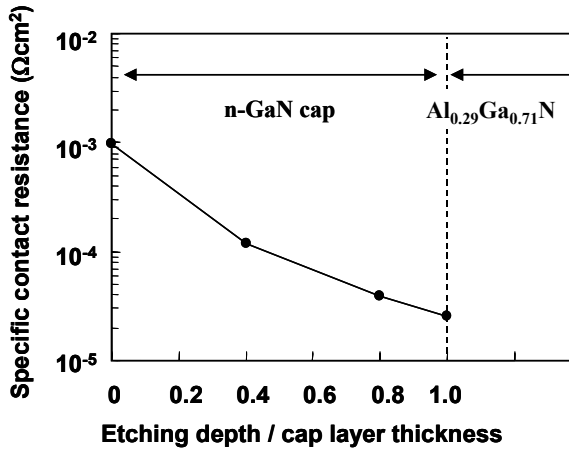


Fig. 2 Etching depth dependence of specific contact resistance.

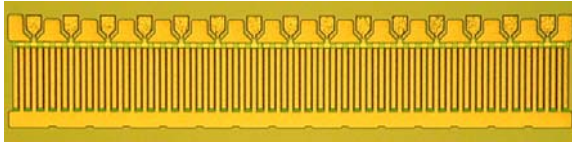


Fig. 3. Photograph of AlGaIn/GaN HEMT chip. The total gate width is 36 mm with a unit gate width of 400 μm.

dependence on specific contact resistance. The Al content in the AlGaIn layer was 29 %. Specific contact resistance decreased from $9.80 \times 10^{-4} \Omega\text{cm}^2$ for conventional structure to $2.56 \times 10^{-5} \Omega\text{cm}^2$. These results mean that removing n-GaN cap layer enhanced tunneling transport of electrons.

The current-collapse-free AlGaIn/GaN HEMT die was mounted on a conventional metal/ceramic package. The gate periphery is 36 mm with a unit gate width of 400 μm, as shown in Fig. 3. A single-chip amplifier was designed for W-CDMA base station applications with a frequency of 2.1 GHz. Quiescent drain current (I_{dsq}) is 1.4% I_{fmax} near class B, which is mainly used in base station system [6]. We measured all performance using a packaged chip on a test-fixture, which was tuned at 30 V drain bias voltage. When we changed the drain voltage, the matching conditions remained the same.

RESULTS AND DISCUSSION

1) DC & RF Characteristics: Figure 4 shows I-V characteristics. Good pinched-off characteristics were obtained. On-state and off-state breakdown voltages were over 100 V and 160 V respectively. Figure 5 shows pulsed I-V characteristics. Power operation was obtained with device biased at 50V in class B. Pulsed mode on-resistance (R_{on}) did not increase compared with DC-mode, indicating that

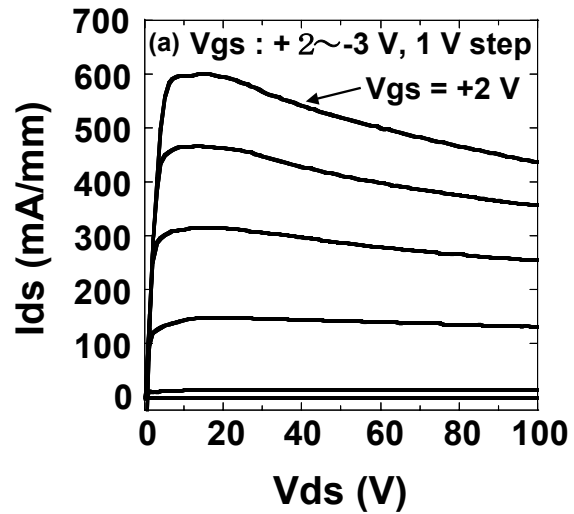


Fig. 4. I-V characteristics of 40-μm gate periphery. 100 V operations were studied using (a) a semiconductor parameter analyzer and (b) a 100-Hz curve tracer.

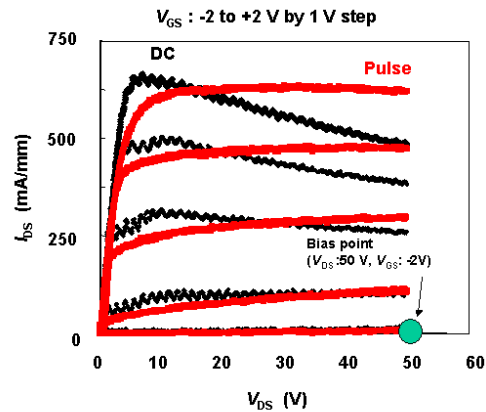


Fig. 5. Pulsed I-V characteristics. Bias point was V_{ds} of 50 V and V_{gs} of -2 V. Pulse period and pulse duration are 1 ms and 1 μs, respectively.

current collapse can be suppressed with our proposed device structure.

2) Power performance: Figure 6 shows power performance measured at V_{ds} equal to 63 V. A state-of-the-art 150 W CW saturation power was achieved with a PAE of 54% and a linear gain of 12.9 dB. Figure 7 shows the drain supply voltage dependence of the power amplifier performance. The PAE decline is drastically improved due to the current-collapse-free operation. We also obtained the record saturated peak power of 174 W in practical 4-carrier W-CDMA modulation scheme [6].

3) Distortion characteristics: We reported previously [4] that superior linearity can be obtained at V_{ds} equal to 30 V for a 1mm-gate periphery AlGaIn/GaN HEMT. In this paper, a larger gate periphery is investigated and the intermodulation results are in Figure 8. Tone spacing is 1 MHz. A simple IM_3 profile could also be obtained for a large gate-periphery device at V_{ds} equal to 24V. However, at 50V, IM_3 profile

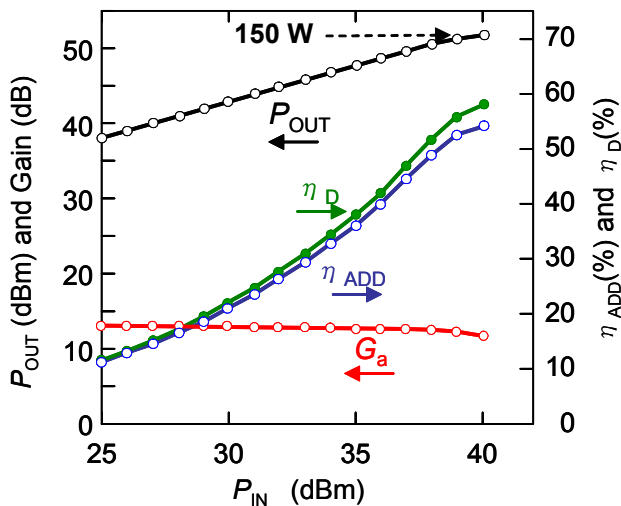


Fig. 6. CW power measurement results of single-chip AlGaIn/GaN HEMT amplifier at 2.1 GHz. Quiescent drain current is 500 mA at $V_{DS}=63$ V.

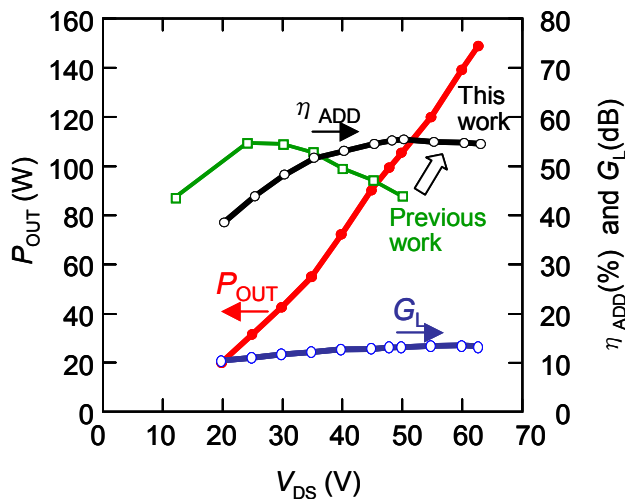


Fig. 7. Drain supply voltage dependence of output power P_{OUT} , Gain G_L and power-added efficiency PAE of AlGaIn/GaN HEMT amplifier at 2.1 GHz.

had sweet spot feature [5]. We performed the measurement with the same matching circuit as 24V, so the tuning condition was not optimized for 50V operation. We believe optimized tuning for 50V gives a simple IM_3 profile as good as 24V. Figure 9 shows the difference of upper sideband IM_3 and lower sideband IM_3 . This memory effect is important for digital pre-distortion system in IMT-2000 [4]. As shown in Fig. 9, the difference of upper IM_3 and lower IM_3 is quite small for a wide range of output power for 50V operation.

4) Reliability: We investigated reliability performance, a very important issue at high drain bias operation. The RF-stress test was examined under P_{3dB} conditions at V_{ds} between 30-60 V as shown in Fig. 10. To accelerate the aging test, P_{out} and Gain decreased almost 0.2 dBm within one hour, when operated at 30-40 V [8]. Now, with our newly improved collapse-free AlGaIn/GaN HEMTs operated at 60 V, showed no degradation of power and gain for 1000 h. This is the first report of stable operation at 60 V.

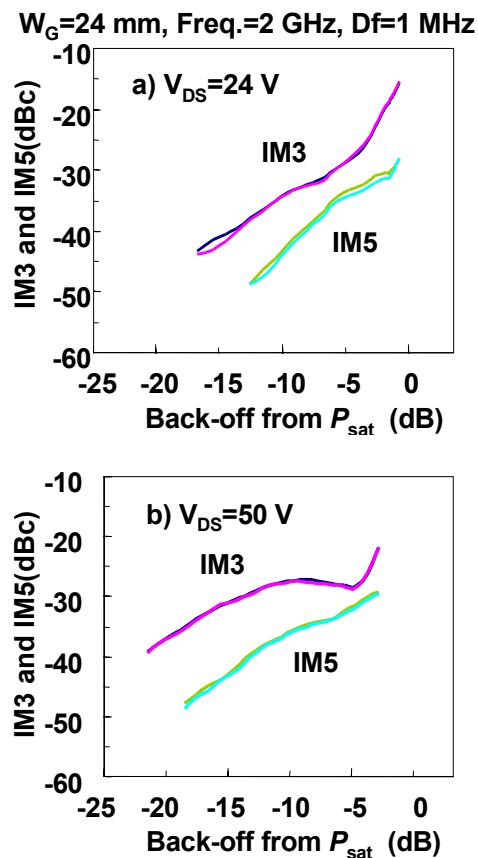


Fig. 8. 2-tone intermodulation characteristics measured at a) 24 V and b) 50 V. Measured frequency is 2.2 GHz. I_{dsq} is 1.4% I_{fmax} near class-B. Gate width is 24 mm. Tone spacing is 1 MHz. Both upper and lower distortions are shown in this figure.

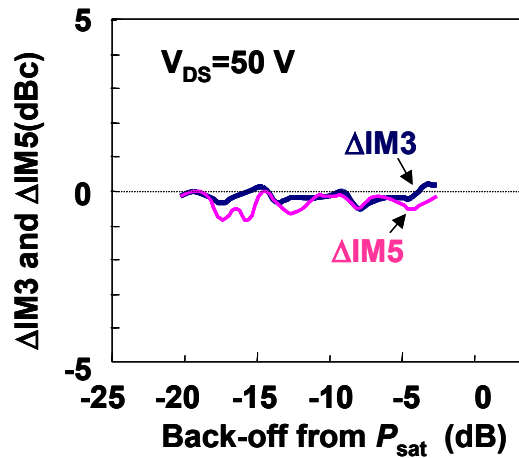


Fig. 9. Memory effect of GaN-HEMT at V_{ds} of 50 V. Difference between upper distortions and lower distortions are shown in this figure. Gate width is 24 mm. Tone spacing is 1 MHz.

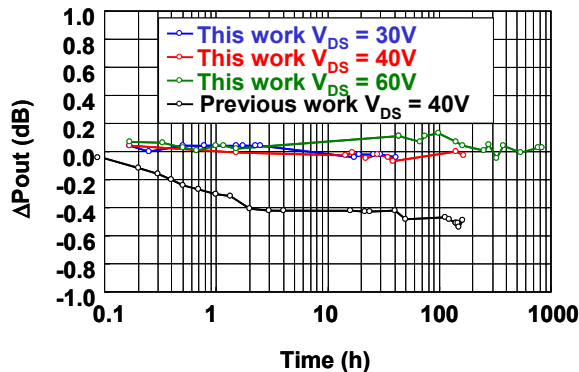


Fig. 10. Power characteristics under P_{3dB} RF-stress test at 30 V, 40 V and 60 V.

CONCLUSIONS

In summary, we have demonstrated successful AlGaIn/GaN HEMT operation with no current collapse at high drain bias voltages of up to 63 V. To our knowledge, the AlGaIn/GaN HEMT single chip amplifier exhibited the highest saturated peak power of 150 W in CW mode and the highest saturated peak power of 174 W in W-CDMA modulation reported so far. RF-stress test under P_{3dB} showed stable performance up to 60 V for 1000 h, for the first time. These results are very promising for application of AlGaIn/GaN HEMTs to the wireless infrastructure market, especially 3rd-generation base station power amplifiers.

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